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(54) Title: DRYING DEVICE

(54) 发明名称: 干燥装置

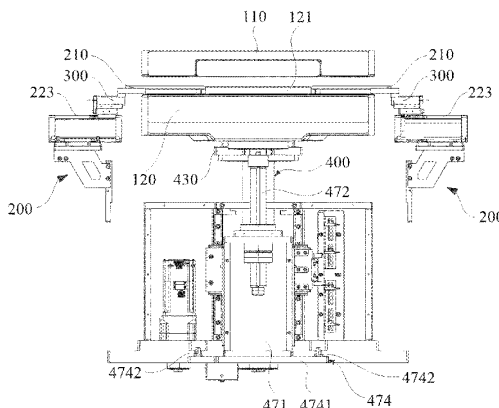


图 1

(57) Abstract: Disclosed in the present invention is a drying device, comprising an upper chamber, a lower chamber, a supporting assembly, a measurement part and a lifting mechanism. The supporting assembly is arranged at a preset height position and comprises a supporting part and a driving mechanism, the driving mechanism being used for driving the supporting part to move in a horizontal direction. The measurement part is arranged on the supporting assembly, and the lifting mechanism is arranged below the lower chamber. When the supporting part horizontally moves inwards to a reception position and is connected to a substrate, the measurement part measures process parameters of the substrate, and the lifting mechanism drives the lower chamber to move upwards in a vertical direction to the reception position, such that the substrate is transferred from the supporting part to a substrate tray and is carried by the substrate tray; then the supporting part horizontally moves outwards to a clearance position, and then the lifting mechanism continues

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to drive the lower chamber to move upwards to a process position, such that the lower chamber and the upper chamber are closed to form a closed chamber. The present invention enables the measurement part to have more accurate measurement values, and meanwhile shortens the whole process time of a drying treatment process.

(57) 摘要: 本发明公开了一种干燥装置, 包括上腔体、下腔体、支撑组件、检测部和举升机构, 支撑组件设置在预定高度位置处, 且包括支撑部和驱动机构, 驱动机构用于驱动支撑部沿水平方向移动, 检测部设置在支撑组件上, 举升机构设置在下腔体的下方。当支撑部向内水平移动至接片位置并接到基板时, 检测部检测基板的工艺参数, 举升机构带动下腔体沿竖直方向向上运动至接片位置, 使基板由支撑部移交至基板托盘并由基板托盘承载, 接着支撑部向外水平移动至避让位置, 之后举升机构继续带动下腔体向上运动至工艺位置, 使得下腔体与上腔体闭合形成密闭腔室。本发明能够使得检测部检测数值更准确, 同时缩短了干燥处理过程的整个工艺时间。